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METHOD AND APPARATUS FOR LOW TEMPERATURE SELECTIVE EPITAXY IN A DEEP TRENCH

Abstract

Embodiments of the present disclosure generally relate to methods for forming epitaxial layers on a semiconductor device. In one or more embodiments, methods include removing oxides from a substrate surface during a cleaning process, flowing a processing reagent containing a silicon source and exposing the substrate to the processing reagent during an epitaxy process, and stopping the flow of the processing reagent. The method also includes flowing a purging gas and pumping residues from the processing system, flowing an etching gas and exposing the substrate to the etching gas. The etching gas contains hydrogen chloride and at least one germanium and/or chlorine compound. The method further includes stopping the flow of the at least one compound while continuing the flow of the hydrogen chloride and exposing the substrate to the hydrogen chloride and stopping the flow of the hydrogen chloride.

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Background/Summary

CROSS-REFERENCE TO RELATED APPLICATIONS [0001] This application is a continuation application of U.S. application Ser. No. 17/961,463, filed Oct. 6, 2022, which is a continuation application of U.S. application Ser. No. 15/889,669, filed Feb. 6, 2018, now abandoned, which claims benefits of U.S. Prov. Appl. No. 62/457,572, filed Feb. 10, 2017, which are incorporated herein by reference.

FIELD

[0002] Implementations of the disclosure generally relate to the field of semiconductor manufacturing processes, more particularly, to a cluster tool and methods of depositing silicon-containing films for forming semiconductor devices.

BACKGROUND

[0003] Low temperature epitaxy has a distinct advantage of yielding epitaxial films with very high degree of dopant activation. Epitaxial films with high dopant activation can be useful for contact applications in the CMOS manufacturing process where thermal budget needs to be at or below certain temperature, such as 450° C., in order to preserve the high-K metal gate stack in the middle-of-line (MOL) fabrication process.

[0004] There is a need in the art to integrate low temperature epitaxy for growing phosphorous-containing silicon layer in order to enable orders of magnitude reduction in contact resistance of nMOS transistors.

SUMMARY

[0005] The present disclosure generally relate to a cluster tool and methods for forming an epitaxial layer on a semiconductor device. In one implementation, the cluster tool includes a transfer chamber, a pre-clean chamber coupled to the transfer chamber, a plasma-cleaning chamber coupled to the transfer chamber, a deposition chamber coupled to the transfer chamber, an etch chamber coupled to the transfer chamber, and a thermal process chamber coupled to the transfer chamber.

[0006] In another implementation, the cluster tool includes a transfer chamber coupled to a load-lock chamber, a first cleaning chamber coupled to the transfer chamber, the first cleaning chamber comprising a capacitively coupled plasma source and a substrate support coupling to a bias RF power supply, a second cleaning chamber coupled to the transfer chamber, the second cleaning

chamber comprising an inductively coupled plasma source, an epitaxial deposition chamber coupled to the transfer chamber, the epitaxy chamber comprising a liquid vaporizer in fluid communication with a liquid precursor source, an etch chamber coupled to the transfer chamber, and a thermal process chamber coupled to the transfer chamber.

Description

BRIEF DESCRIPTION OF THE DRAWINGS

[0007] Implementations of the present disclosure, briefly summarized above and discussed in greater detail below, can be understood by reference to the illustrative implementations of the disclosure depicted in the appended drawings. It is to be noted, however, that the appended drawings illustrate only typical implementations of this disclosure and are therefore not to be considered limiting of its scope, for the disclosure may admit to other equally effective implementations.

[0008] FIG. 1 is a flow chart illustrating a method of forming an epitaxial layer according to one implementation of the present disclosure.

[0009] FIG. 2 is a cross-sectional view of a processing chamber that may be used to perform a cleaning process found in FIG. 1.

[0010] FIG. 3 is a cross-sectional view of a plasma-cleaning chamber that may be used to perform a cleaning process found in FIG. 1.

[0011] FIG. 4 is a cross-sectional view of a thermal processing chamber that may be used to perform an epitaxial process found in FIG. 1.

[0012] FIG. 5 is a cross-sectional view of an ICP plasma chamber that may be used to perform etch processes found in FIG. 1.

[0013] FIG. 6 is a schematic, cross-sectional view of a processing system that may be used for temperature-controlled processing of substrates.

[0014] FIG. 7 is a schematic top view of a processing system that can be used to complete the flow chart of FIG. 1.

[0015] To facilitate understanding, identical reference numerals have been used, where possible, to designate identical elements that are common to the figures. The figures are not drawn to scale and may be simplified for clarity. It is contemplated that elements and features of one implementation may be beneficially incorporated in other implementations without further recitation.

DETAILED DESCRIPTION

[0016] FIG. 1 is a flow chart **100** illustrating a method of forming an epitaxial layer according to one implementation of the present disclosure. The method begins at block **102** where a substrate is pre-cleaned. The substrate may be a wafer or any object having native oxides. The substrate may contain monocrystalline surfaces and/or one secondary surface that is non-monocrystalline, such as polycrystalline or amorphous surfaces. Monocrystalline surfaces may include the bare crystalline substrate or a deposited single crystal layer usually made from a material such as silicon, germanium, silicon germanium or silicon carbon. Polycrystalline or amorphous surfaces may include dielectric materials, such as oxides or nitrides, specifically silicon oxide or silicon nitride, as well as amorphous silicon surfaces.

[0017] Any suitable cleaning process that removes oxides from the substrate without significantly damaging the substrate may be used. Suitable cleaning processes include sputter etch processes, plasma-based oxide etch processes, wet etch processes, or combinations thereof. Exemplary plasma-based oxide etch processes include NF.sub.3/NH.sub.3 inductively coupled plasma processes or NF.sub.3/NH.sub.3 capacitively coupled plasma processes. In one implementation, the plasma-based oxide etch process is a remote plasma assisted dry etch process which involves the simultaneous exposure of a substrate to NF.sub.3 and NH.sub.3 plasma by-products. In one

example, the plasma-based oxide etch process may be similar to or may include a SICONI® etch process that is available from Applied Materials, Inc. of Santa Clara, Calif. The SICONI® etch process may be performed in a SICONI® Preclean chamber, available from Applied Materials, Inc. of Santa Clara, California. One exemplary SICONI® Preclean chamber is shown in FIG. 2 and will be discussed below.

[0018] In some implementations that use remote plasma, excitation of the gas species allows plasma-damage-free substrate processing. The remote plasma etch can be largely conformal and selective towards silicon oxide layers, and thus does not readily etch silicon regardless of whether the silicon is amorphous, crystalline or polycrystalline. The remote plasma process will generally produce solid by-products which grow on the surface of the substrate as substrate material is removed. The solid by-products can be subsequently removed via sublimation when the temperature of the substrate is raised (e.g., 300° C.). The plasma etch process results in a substrate surface having silicon-hydrogen (Si—H) bonds thereon.

[0019] In some implementations, the cleaning process may be performed in a processing chamber using a remote plasma source. For example, the processing chamber may be an AKTIV® Pre-Clean chamber, available from Applied Materials, Inc. of Santa Clara, California. One exemplary etch chamber using ICP source is shown in FIG. 3 and will be discussed below.

[0020] In some implementations, the cleaning process may be performed in an etch chamber using an inductively coupled plasma (ICP) source. For example, the etch chamber may be a Centura® Advantedge™ Mesa™ etch chamber, available from Applied Materials, Inc. of Santa Clara, California. Alternatively, the cleaning process may be performed in an etch chamber employing a radical-based chemistry. One exemplary etch chamber using ICP source is shown in FIG. 5 below.

[0021] If desired, the block **102** may include additional preparation steps. For example, the block **102** may include pre-baking the substrate to further clean the surface. The pre-bake may be performed in the presence of hydrogen at a temperature of about 330° C. In such a case, the pre-bake may be done in an epitaxy chamber, such as one shown in FIG. 4 below. The pre-bake may include raising the temperature of the substrate to about 330° C. In some implementations, the block **102** includes an HF clean of the substrate, which may result in-H terminations on the silicon (monocrystalline) surfaces and —OH termination on the oxide (dielectric) surfaces.

[0022] At block **104**, the substrate is exposed to a processing reagent in, for example, a gas phase epitaxy chamber at a target temperature for epitaxial deposition of a silicon-containing layer. An exemplary epitaxy chamber that may be used is a Centura® RP EPI chamber, available from Applied Materials, Inc., of Santa Clara, California. One exemplary epitaxy chamber is shown below in FIG. 4. It is contemplated that other chambers, including those available from other manufacturers, may be used to practice epitaxial deposition.

[0023] The target temperature for epitaxial deposition may be between about 250° C. and about 600° C., such as about 300° C. to about 500° C., for example about 350° C. to about 400° C. The pressure within the epitaxy chamber is kept relatively low, for example less than about 50 Torr, such as about 10 Torr to about 40 Torr. The processing reagent may include one or more deposition gases and at least one dopant gas. The deposition gas may include one or more precursor gases selected from Group III precursor gas, Group V precursor gas, Group VI precursor gas, or Group IV precursor gas. In cases where a silicon-containing epitaxial layer is formed, the deposition gas may contain at least a silicon source. Exemplary silicon sources may include, but are not limited to, silanes, halogenated silanes, silicon tetrachloride (SiCl₄), or any combinations thereof. Silanes may include silane (SiH₄) and higher silanes with the empirical formula Si_xH_(2x+2), such as disilane (Si₂H₆), trisilane (Si₃H₈), tetrasilane (Si₄H₁₀), pentasilane (Si₅H₁₂), or hexasilane (Si₆H₁₄). Other higher silanes, such as a silicon hydride expressed as Si_nH_{2n} (n is a natural number equal to or greater than 3), may also be used. For example, cyclotrisilane (Si₃H₆), cyclotetrasilane (Si₄H₈), cyclopentasilane (Si₅H₁₀), cyclohexasilane (Si₆H₁₂), or cycloheptasilane

(Si.sub.7H.sub.14). Halogenated silanes may include monochlorosilane (MCS), dichlorosilane (DCS), trichlorosilane (TCS), hexachlorodisilane (HCDS), octachlorotrisilane (OCTS), silicon tetrachloride (STC), or a combination thereof. In some implementations, silanes may include higher order silanes with varying degrees of halogenation in the form of —F, Cl, Br or I attached to them in order to enable selectivity. For example, Si.sub.2H.sub.4Cl.sub.2 or Si.sub.3H.sub.5Cl.sub.3 etc.

[0024] In one exemplary implementation, the silicon source comprises tetrasilane. In another exemplary implementation, the silicon source comprises disilane. In yet another exemplary implementation, the silicon source comprises tetrasilane and disilane.

[0025] The dopant gas may include, but is not limited to phosphorous, boron, arsenic, gallium, or aluminum, depending on the desired conductive characteristic of the deposited epitaxial layer. The deposition gas may optionally contain at least one secondary elemental source, such as a germanium source or a carbon source. Depending on application, other elements, such as metals, halogens or hydrogen may be incorporated within a silicon-containing layer. In one exemplary implementation, the silicon-containing epitaxial layer is phosphorous doped silicon (Si:P), which can be achieved using a dopant such as phosphine (PH.sub.3), phosphorus trichloride (PCl.sub.3), phosphorous tribromide (PBr.sub.3), and phosphates such as tributyl phosphate (TBP).

[0026] The processing reagents may optionally include a carrier gas. The carrier gas may be selected based on the precursor(s) used and/or the process temperature during the epitaxial process. Suitable carrier gases include nitrogen, hydrogen, argon, helium, or other gases which are inert with respect to the epitaxial process. Nitrogen may be utilized as a carrier gas in implementations featuring low temperature (e.g., <600° C.) processes. The carrier gas may have a flow rate from about 1 SLM (standard liters per minute) to about 100 SLM, such as from about 3 SLM to about 30 SLM.

[0027] Table 1 below illustrates selective growth rate of a phosphorous-containing epitaxial layer (Si:P) formed using different silicon sources (tetrasilane vs disilane) under given process conditions. In all examples shown in Table 1, tetrasilane was provided at a flow rate of about 11 sccm, and disilane was provided at a flow rate of about 90 sccm. Phosphine was provided at a flow rate of about 1000 sccm (tetrasilane) and about 300 sccm (disilane). Hydrogen (not shown), which serves as a carrier gas, was provided at a flow rate of about 8000 sccm. In all examples, the processing chamber was heated and maintained at about 400° C. to about 500° C., with a chamber pressure of about 40 Torr. The process conditions described herein and throughout this disclosure are based on a 300 mm diameter substrate. As can be seen in Table 1 below, the silicon source using tetrasilane at 500° C. provides a superior growth rate than the silicon source using disilane, even though tetrasilane is flowed at a much less amount than disilane.

TABLE-US-00001 TABLE 1 Thickness/ Silicon Strain %- Growth Source Condition Flows/Time
XRD Rate Tetrasilane 400° C./40T Si.sub.4H.sub.10: 11 sccm/PH3: 270 Å/1.4% 5 Å/min
(Si.sub.4H.sub.10) 1000 sccm/Time: 3000 s Tetrasilane 450° C./40T Si.sub.4H.sub.10: 11
sccm/PH3: 450 Å/1.3% 37 Å/min (Si.sub.4H.sub.10) 1000 sccm/Time: 712 s Tetrasilane 500°
C./40T Si.sub.4H.sub.10: 11 sccm/PH3: 796 Å/1.3% 239 Å/min (Si.sub.4H.sub.10) 1000
sccm/Time: 200 s Disilane 450° C./40T Si.sub.2H.sub.6: 90 sccm/PH3: 265 Å/1.4% 9 Å/min
(Si.sub.2H.sub.6) 300 sccm/Time: 1800 s Disilane 475° C./40T Si.sub.2H.sub.6: 90 sccm/PH3: 540
Å/1.1% 18 Å/min (Si.sub.2H.sub.6) 300 sccm/Time: 1800 s Disilane 500° C./40T
Si.sub.2H.sub.6: 90 sccm/PH3: 550 Å/1.0% 165 Å/min (Si.sub.2H.sub.6) 300 sccm/Time: 200 s

[0028] In some implementations where disilane is used as a silicon source, the processing reagent may further include a halogen precursor. Exemplary halogen precursors may be those containing halogen molecules, such as chlorine gas or hydrogen chloride. The halogen precursor may be flowed simultaneously or concurrently with the deposition gas (i.e., co-flow mode) during the epitaxial process. In such a case, the deposition gas and the halogen precursor may be separately flowed into the epitaxy chamber. The deposition gas and the halogen precursor may be pre-mixed

and formed as a gas mixture before flowing into the epitaxy chamber. In either case, the flow ratio of the deposition gas and the halogen precursor in the epitaxy chamber may be about 1:1.5 to about 1:3, for example about 1:2. It is contemplated that disilane and chlorine gas mentioned herein can be replaced with any other silicon source and halogen precursor using the flow ratio described herein.

[0029] At block **106**, once a desired thickness of the silicon-containing epitaxial layer has been formed on the substrate, the flow of the processing reagent is discontinued and any reaction residues and/or unwanted gases are pumped out of the epitaxy chamber. During block **106**, the pressure within the epitaxy chamber is maintained at about 1 Torr to about 30 Torr, such as about 1.5 Torr to about 15 Torr. A purging gas, such as hydrogen or argon, may be introduced into the epitaxy chamber to allow processing reagent and residues to be pumped from the epitaxy chamber while maintaining the epitaxy chamber at a required chamber pressure. The purging time may vary between about 5 seconds to about 45 seconds, for example about 15 seconds to about 20 seconds.

[0030] At block **108**, the flow of the purging gas is discontinued and the substrate is exposed to an etching gas to selectively remove amorphous material, for example amorphous silicon (a-Si), from dielectric surfaces of the substrate. The etching process may be performed in an etching chamber, such as one shown in FIG. 3 or FIG. 5.

[0031] The etching gas may include at least one etchant and a carrier gas. The etchant may be a halogen-containing etchant. Exemplary etchant may include, but is not limited to hydrogen chloride (HCl), germanium hydride (GeH₄), chlorine (Cl₂), boron trichloride (BCl₃), phosphorus trichloride (PCl₃), or any combinations thereof. Higher order germanes such as digermane (Ge₂H₆) or trigermane (Ge₃H₈), or chlorinated germane gas such as germanium tetrachloride (GeCl₄), dichlorogermane (GeH₂Cl₂), trichlorogermane (GeHCl₃), hexachlorodigermane (Ge₂Cl₆), or a combination of any two or more thereof, may also be used. In one implementation, the etchant includes HCl and GeH₄. In another implementation, the etchant includes HCl and PCl₃. In yet another implementation, the etchant includes Cl₂ and PCl₃. In yet one another implementation, the etchant includes HCl, GeH₄ and PCl₃. Any suitable halogenated germanium compounds may also be used.

[0032] The carrier gas may include hydrogen, nitrogen, argon, helium, and any combinations thereof. A carrier gas may be selected based upon specific etchant(s). In one exemplary implementation, the etchant includes HCl and GeH₄. In another implementation, the etchant includes Cl₂ and GeH₄. In cases where HCl and GeH₄ are used during etching, the flow of HCl and GeH₄ may be introduced into the epitaxy chamber at a GeH₄/HCl ratio of about 1:3 to about 1:7, for example about 1:5. In one exemplary example, GeH₄ is introduced at a flow rate of about 60 sccm and HCl is introduced at 300 sccm, with the carrier gas (N₂) introduced at a flow rate of about 3 SLM.

[0033] The etching time may be about 250 seconds to about 850 seconds, for example about 300 seconds to about 800 seconds, for example about 360 seconds to about 480 seconds. During the etch-back, the etching temperature may be about 600° C. or less, for example 500° C. or less, such as about 200° C. to about 400° C. The chamber pressure during etching may be maintained at about 80 Torr to about 300 Torr, such as about 100 Torr to about 200 Torr. The etch-back process may be performed in the epitaxy chamber. It has been observed that the process conditions described herein can minimize epitaxial layer etch while removing all the amorphous silicon growth on dielectric surfaces. Particularly, the addition of GeH₄ or higher order germanes to HCl provide sufficient etching with desired selectivity at lower temperatures of 500° C. or less, which has been a challenging in the past if HCl alone was used for etching.

[0034] Depending on the epitaxial thickness, it has been observed that an amorphous silicon/crystalline epitaxial layer etch selectivity of 30:1 or greater, such as 50:1 or even 80:1 can be achieved at low etching temperatures using the etchants discussed herein. Thus, the result is a

much thinner amorphous silicon layer on the dielectric surface compared to the epitaxial layer on the semiconductor surface due to the etch-back process performed after the epitaxial deposition. [0035] At block **110**, the flow of the etchant, such as GeH.sub.4, may be discontinued and HCl may continue to flow to remove GeH.sub.4 and other reaction residues/byproducts from the substrate. The flow of HCl may be continued for about 5 seconds to about 20 seconds, for example about 10 seconds.

[0036] After block **110**, the substrate may then be subjected to downstream processing, such as thermal annealing, thermal cleaning, thermal chemical vapor deposition, thermal oxidation or thermal nitridation, which may be performed in a temperature controlled processing chamber such as one shown in FIG. 6.

[0037] Alternatively, one or more steps of the method **100** may be repeated until a predetermined thickness (e.g., 5-10 nm) of Si:P epitaxial film has been formed on the target surfaces of the substrate. For example, if the contact trenches on the substrate has a high aspect ratio (10:1 or higher), blocks **104**, **106**, **108** and **110** may be repeated for 2 to 5 cycles to maximize etching of unwanted films from the dielectric surfaces at or near the bottom trench.

[0038] It should be noted that the concept described in implementations of the present disclosure is also applicable to epitaxy process for forming other materials. Some possible examples may include undoped silicon, SiGe/SiGe:B, Si:CP, pure Ge, GeSn, GeP, GeB, or GeSnB, etc., which may be used in logic and memory applications. In such cases, possible silicon precursors or dopant gases may be the same as those described above, and possible germanium precursors may include, but are not limited to GeH.sub.4, Ge.sub.2H.sub.6, or halogenated germanium such as GeCl.sub.4, GeHCl.sub.3, Ge.sub.2Cl.sub.6, Ge.sub.3Cl.sub.8, etc.

[0039] FIG. 2 is a cross-sectional view of a processing chamber **200** that may be used to perform the cleaning process found in block **102**. The processing chamber **200** may be particularly useful for performing a thermal or plasma-based oxidation process and/or a plasma assisted dry etch process. The processing chamber **200** includes a chamber body **212**, a lid assembly **214**, and a support assembly **216**. The lid assembly **214** is disposed at an upper end of the chamber body **212**, and the support assembly **216** is at least partially disposed within the chamber body **212**. A vacuum system can be used to remove gases from processing chamber **200**. The vacuum system includes a vacuum pump **218** coupled to a vacuum port **221** disposed in the chamber body **212**. The processing chamber **200** also includes a controller **202** for controlling processes within the processing chamber **200**.

[0040] The lid assembly **214** includes at least two stacked components configured to form a plasma volume or cavity there between. A first electrode **220** is disposed vertically above a second electrode **222** confining a plasma volume therebetween. The first electrode **220** is connected to a power source **224**, such as a radio frequency (RF) power supply, and the second electrode **222** is connected to ground or a source return, forming a capacitance between the first electrode **220** and the second electrode **222**. The lid assembly **214** also includes one or more gas inlets **226** for providing a cleaning gas to a substrate surface through a blocker plate **228** and a gas distribution plate **230**, such as a showerhead. The cleaning gas may be an etchant or ionized active radical, such as ionized fluorine, chlorine, or ammonia, or an oxidizing agent, such as ozone.

[0041] Alternatively, a different cleaning process may be utilized to clean the substrate surface. For example, a remote plasma containing He and NF.sub.3 may be introduced into the processing chamber **200** through the gas distribution plate **230**, while NH.sub.3 may be directly injected into the processing chamber **200** via a separate gas inlet **225** that is disposed at a side of the chamber body **212**.

[0042] The support assembly **216** may include a substrate support **232** to support a substrate **210** thereon during processing. The substrate support **232** has a flat substrate supporting surface for supporting the substrate to be processed thereon. The substrate support **232** may be coupled to an actuator **234** by a shaft **236** which extends through a centrally-located opening formed in a bottom

of the chamber body **212**. The actuator **234** may be flexibly sealed to the chamber body **212** by bellows (not shown) that prevent vacuum leakage from around the shaft **236**. The actuator **234** allows the substrate support **232** to be moved vertically within the chamber body **212** between a process position and a lower, transfer position. The transfer position is slightly below the opening of a slit valve formed in a sidewall of the chamber body **212**. In operation, the substrate support **232** may be elevated to a position in close proximity to the lid assembly **214** to control the temperature of the substrate **210** being processed. As such, the substrate **210** may be heated via radiation emitted or convection from the distribution plate **230**.

[0043] A bias RF power supply **280** may be coupled to the substrate support **232** via a cable **282** through a matching network **284**. The bias RF power supply **280** provides a bias to the substrate **210** to direct the ionized cleaning gas toward the substrate **210**.

[0044] FIG. **3** is a cross-sectional view of a plasma-cleaning chamber **300** that may be used to perform the cleaning process found in block **102**. The processing chamber **300** has a chamber body **310** that includes a chamber adapter **316**, an adapter **318** and a lid **340**. The chamber adapter **316** and the lid **340** may be fabricated from aluminum, stainless steel or other suitable materials. The lid **340** is removably coupled to the chamber adapter **316** to define a process region **330** therein.

[0045] A heater (or pedestal) **314** is disposed in the process region **330** of the chamber body **310**. The heater **314** is coupled to a bottom of the chamber adapter **316** through a central shaft. The heater **314** has a substrate supporting surface for supporting the substrate **308** thereon during a process, such as cleaning of the surface of the substrate described above with respect to box **104**. The heater **314** may be fabricated from bare aluminum with sapphire contact. The heater **314** is actuated to move vertically between a loading position and a processing position. The heater **314** may be utilized to provide temperature to the substrate **308**, thereby heating or cooling the substrate during process. In some implementations, the heater **314** may use a ring-like substrate support (not shown) to support and lift up the substrate **308** from the edge of the substrate when the heater **314** is lowered down to the loading position. During the process, the heater **314** is raised up to the processing position, which picks up and supports the substrate **308** with its substrate supporting surface at a desired height for processing of the substrate **308**.

[0046] In some implementations, the heater **314** may support an optional focus ring **338** disposed on its outer periphery. The focus ring **338** circumscribes the substrate **308** during processing. In one example, the focus ring **338** is fabricated from quartz.

[0047] The adapter **318** is disposed between the lid **340** and the chamber adapter **316** and supports a gas distribution plate **326** thereon. The gas distribution plate **326** may be a quartz showerhead. A plenum **348** is defined between the gas distribution plate **326** and the lid **340**. The gas distribution plate **326** includes a plurality of apertures **327** to allow gases flowing into the plenum **348** through a port **342** formed in the lid **340** to be distributed across the substrate **308** disposed in the process region **330**.

[0048] An opening **315** is formed at the bottom of the chamber adapter **316** and is connected to a pump **317**. The pump **317** may be used to control the pressure inside the chamber body **310** from between about 1 mTorr and about 500 Torr. For example, the pump **317** may be a low pressure pump that maintains the pressure inside the chamber body **310** at an exemplary pressure range of about 10 mTorr to about 500 mTorr. The pump **317** may also be a turbo pump that maintains the pressure inside the chamber body **310** at an exemplary pressure range of about 20 Torr to 300 Torr.

[0049] A remote plasma source **350** is coupled to the port **342** by a passage **360**. The passage **360** defines a conduit **356** through which the reactive radicals generated in the remote plasma source **350** are filtered before entering the process region **330**. The reactive radicals generated therefrom may include ions, charged species, and other reactive species. In one implementation, the gases flowing through the conduit **356** are filtered by a magnetic field generated by one or more magnets disposed adjacent to the passage **360**. The magnets generate a magnetic field across the passage **360** to filter charged particles entrained with the reactive radicals flowing from the remote plasma

source **350**.

[0050] In the implementation depicted in FIG. 3, a first magnet **352** and a second magnet **354** are disposed adjacent the passage **360**. The magnets **352**, **354** may be disposed to oppose to each other across the passage **360**. For example, the magnets **352**, **354** may be adhered or secured on opposite sides of an outer periphery of the passage **360**. It is also contemplated that the magnets **352**, **354** may be secured to the chamber lid **340** or other components of the chamber body **310**. The relative distance between the opposed magnet and the conduit **356** formed within the passage **360** affects the strength of the magnetic field passing through the conduit **356**, and thereby affects the filtering efficiency. The magnetic field may also be adjusted by using different magnets, i.e., replacing magnets **352**, **354** with different strength. The passing charged particles are drawn in contact with an inner surface **370** of the passage **360** and become electrically neutral, non-ionic species. As such, the filtered, electrically neutral radicals are delivered to the surface of the substrate to react with and clean oxides and/or contaminants thereon.

[0051] In some implementations, the reactive radicals may be further filtered by providing a quartz surface in the flow path of the process gases (i.e., reactive radicals) passing into the chamber body **310**. For example, the inner surface **370** of the passage **360** defining the conduit **356** connecting the remote plasma source **350** and the chamber body **310** may be entirely or partially coated or fabricated from quartz. Additionally, the surfaces defining the plenum **348** and/or gas distribution plate **326** may also be entirely or at least partially coated or fabricated from quartz. For example, in the implementation of FIG. 3, a quartz ring **324** may circumscribe the outer boundary of the plenum **348**. Additionally, a quartz liner **344** may be disposed on the bottom surface of the lid **340** defining the upper boundary of the plenum **348**.

[0052] The inner surface **370** of the passage **360** serves as an ion filter to reduce the recombination of the radicals by providing a quartz surface with which hydrogen-containing radicals can hydrogen bond and absorb onto the quartz surface. Hydrogen-containing radicals that impinge on the inner surface **370** release an absorbed hydrogen-containing radical into the energized gas, thereby regenerating hydrogen radicals. The hydrogen ions are not regenerated by the inner surface **370**, and thus these ions recombine to form electrically neutral, non-ionic species. Thus, by passing the activated cleaning gas over the quartz surface, the reactive radicals are effectively filtered from the energized cleaning gas, while the radical species are preserved. The charged particles from recombined active radical are efficiently reduced.

[0053] FIG. 4 is a cross-sectional view of a thermal processing chamber **400** that may be used to perform the epitaxial process found in block **104**. The processing chamber **400** includes a chamber body **402**, support systems **404**, and a controller **406**. The chamber body **402** includes an upper portion **412** and a lower portion **414**. The upper portion **412** includes the area within the chamber body **402** between the upper dome **416** and a substrate **210**. The lower portion **414** includes the area within the chamber body **402** between a lower dome **430** and the bottom of the substrate **210**. Deposition processes generally occur on the upper surface of the substrate **210** within the upper portion **412**.

[0054] The support system **404** includes components used to execute and monitor pre-determined processes, such as the growth of epitaxial films in the processing chamber **400** as discussed above in block **104**. A controller **406** is coupled to the support system **404** and is adapted to control the processing chamber **400** and support system **404**. The controller **406** includes a central processing unit (CPU), a memory, and support circuits.

[0055] The processing chamber **400** includes a plurality of heat sources, such as lamps **435**, which are adapted to provide thermal energy to components positioned within the process chamber **400**. For example, the lamps **435** may be adapted to provide thermal energy to the substrate **210**, a susceptor **426**, and/or the preheat ring **423**. The lower dome **430** may be formed from an optically transparent material, such as quartz, to facilitate the passage of thermal radiation therethrough. It is contemplated that lamps **435** may be positioned to provide thermal energy through the upper dome

416 as well as the lower dome **430**.

[0056] The chamber body **402** includes a plurality of plenums formed therein. The plenums are in fluid communication with one or more gas sources **476**, such as a carrier gas, and one or more precursor sources **478**, such as deposition gases and dopant gas discussed above in block **104**. For example, a first plenum **420** may be adapted to provide a deposition gas **450** therethrough into the upper portion **412** of the chamber body **402**, while a second plenum **421** may be adapted to exhaust the deposition gas **450** from the upper portion **412**. In such a manner, the deposition gas **450** may flow parallel to an upper surface of the substrate **210**.

[0057] In cases where a liquid precursor (e.g., tetrasilane) is used, the thermal processing chamber **400** may include a liquid vaporizer **480** in fluid communication with a liquid precursor source **482**. The liquid vaporizer **480** is be used for vaporizing liquid precursors to be delivered to the thermal processing chamber **400**. While not shown, it is contemplated that the liquid precursor source **482** may include, for example, one or more ampules of precursor liquid and solvent liquid, a shut-off valve, and a liquid flow meter (LFM).

[0058] A substrate support assembly **432** is positioned in the lower portion **414** of the chamber body **402**. The substrate support **432** is illustrated supporting a substrate **210** in a processing position. The substrate support assembly **432** includes a susceptor support shaft **427** formed from an optically transparent material and the susceptor **426** supported by the susceptor support shaft **427**. A shaft **460** of the susceptor support shaft **427** is positioned within a shroud **431** to which lift pin contacts **442** are coupled. The susceptor support shaft **427** is rotatable in order to facilitate the rotation of the substrate **210** during processing. Rotation of the susceptor support shaft **427** is facilitated by an actuator **429** coupled to the susceptor support shaft **427**. The shroud **431** is generally fixed in position, and therefore, does not rotate during processing. Support pins **437** couple the susceptor support shaft **427** to the susceptor **426**.

[0059] Lift pins **433** are disposed through openings (not labeled) formed in the susceptor support shaft **427**. The lift pins **433** are vertically actuatable and are adapted to contact the underside of the substrate **210** to lift the substrate **210** from a processing position (as shown) to a substrate removal position.

[0060] The preheat ring **423** is removably disposed on a lower liner **440** that is coupled to the chamber body **402**. The preheat ring **423** is disposed around the internal volume of the chamber body **402** and circumscribes the substrate **210** while the substrate **210** is in a processing position. The preheat ring **423** facilitates preheating of a process gas as the process gas enters the chamber body **402** through the plenum **420** adjacent to the preheat ring **423**.

[0061] The central window portion **415** of the upper dome **416** and the bottom portion **417** of the lower dome **430** may be formed from an optically transparent material such as quartz. The peripheral flange **419** of the upper dome **416**, which engages the central window portion **415** around a circumference of the central window portion **415**, the peripheral flange **421** of the lower dome **430**, which engages the bottom portion around a circumference of the bottom portion, may all be formed from an opaque quartz to protect the O-rings **422** proximity to the peripheral flanges from being directly exposed to the heat radiation. The peripheral flange **419** may be formed of an optically transparent material such as quartz.

[0062] FIG. 5 is a cross-sectional view of an ICP plasma chamber **500** that may be used to perform any of the processes found in blocks **102**, **106**, **108** and **110**. The plasma chamber **500** depicted in FIG. 5 includes an upper portion **528** and a lower portion **530**. The plasma chamber **500** has a sidewall **505** and a lid assembly **510**. The sidewall **505** has an axially symmetrical shape, such as a cylinder. The sidewall **505** includes an axially symmetrical (e.g., cylindrical) dielectric side window **506** and a chamber liner **507**, which may be formed of metal. A substrate support **515** inside the plasma chamber **500** includes a pedestal **520** having a substrate support surface **521** facing the lid assembly **510** for holding a substrate **210**, and a post **525** supporting the pedestal **520**. A processing region **501** of the plasma chamber **500** is confined by the lid assembly **510**, the

pedestal **520** and the sidewall **505**.

[0063] The pedestal **520** may include an insulated internal electrode **524**. Optionally, an electrostatic chucking (ESC) voltage and/or RF plasma bias power may be supplied to the insulated internal electrode **524** via a cable **532** extending through the post **525**. The cable **532** may be coupled to an RF bias power source (such as an RF impedance matching network and/or an RF power generator) as an RF bias feed to the insulated internal electrode **524**.

[0064] The plasma source power is inductively coupled into the processing region **501** by a set of coil antennas, including an inner coil antenna **540**, a middle coil antenna **550** and optionally an outer or side coil antenna **560**, all of which are concentrically disposed with respect to each other and are coaxial with the axis of symmetry of the sidewall **505**. The lid assembly **510** includes a disk-shaped dielectric window **512** through which the inner coil antenna **540** and the middle coil antenna **550** inductively couple RF plasma source power into the processing region **501**. The disk-shaped dielectric window **512** is supported at its periphery by an annular top gas plate **523**. The annular top gas plate **523** surrounds an opening **504**. The disk-shaped dielectric window **512** is coaxial with the sidewall **505** and has a disk-plane parallel with the plane of the substrate support surface **521**. The side coil antenna **560** inductively couples RF plasma source power into the processing region **501** through the cylindrical dielectric side window **506**.

[0065] A gas injector **514** is located at the center of the disk-shaped dielectric window **512** and surrounded by an annular gas flow plate **516**. The gas flow plate **516** may have a plurality of gas input ports (not shown) configured to provide gas flow path to the gas injector **514**. Cleaning gas or etching gas is injected into the processing region **501** by the gas injector **514**.

[0066] The chamber liner **507** is enclosed within a lower chamber body **570** including a cylindrical lower chamber body sidewall **575** and a lower chamber body floor **580**. The lower chamber body sidewall **575** and the lower chamber body floor **580** enclose an evacuation region **581**. A vacuum pump **590** is disposed in a vacuum pump opening **595** in the lower chamber body floor **580** and is centered relative to the axis of symmetry of the lower chamber body sidewall **575**. A containment wall **596** coaxial with the substrate support **515** and a flexible bellows **597** extending between the pedestal **520** and the containment wall **596** enclose the substrate support **515** in an internal central space **598**. The internal central space **598** is isolated from the volume evacuated by the vacuum pump **590**, including the evacuation region **581** and the processing region **501**.

[0067] The power may be supplied from a common RF source or from different RF sources such as RF matches (RF impedance matching networks) **542** and **544**. An RF impedance matching network may be employed having dual outputs in order to drive two of the coil antennas with a first RF generator, while a second RF generator and a second RF impedance matching network drives the third coil antenna. In one implementation, a single RF power generator may drive all three-coil antennas through an RF impedance matching network having three outputs. Alternatively, three RF generators may separately drive the three coil antennas through three respective RF impedance matching networks. The RF power level applied to the different coil antennas may be separately adjusted in order to control radial distribution of plasma ion density. While described implementations include the three coil antennas **540**, **550** and **560**, other implementations may include only one or two of the three described coil antennas **540**, **550** and **560**.

[0068] FIG. **6** is a schematic, cross-sectional view of a processing system **600** that may be used for temperature-controlled processing of substrates, such as silicon substrates. The processing system **600** includes a processing unit **624** and a first heat unit **608**. The processing unit **624** may be a VANTAGE® RADOX™ RTP chamber, available from Applied Materials, Inc., Santa Clara, CA. The processing unit **624** is capable of providing a controlled thermal cycle that heats a substrate **201** for processes such as, for example, thermal annealing, thermal cleaning, thermal chemical vapor deposition, thermal oxidation or thermal nitridation.

[0069] The processing unit **624** includes a chamber **636** enclosing a process zone **602**. The chamber **636** may be made of stainless steel, aluminum or other suitable materials. The chamber **636** may

also include a gas outlet **618** and a first gas inlet **616** opposing the gas outlet **618**. The chamber **636** may include a substrate support **642** disposed therein for supporting the substrate **201** thereupon during processing in the process zone **602**. The substrate support **642** may include a magnetically levitated rotor **620** and a quartz support cylinder **622** that rotates the substrate **201** during processing. A radiation source **646** directs radiation onto the substrate **201**, and may be positioned below the substrate **201** adjacent a bottom surface **638** of the chamber **636** below a radiation permeable window **644**. In one implementation, the radiation source **646** may include a plurality of heat elements **606**. The plurality of heat elements **606** may include one or more approximately radial heating zones that can be independently modulated to control temperatures across the substrate **201**.

[0070] In one implementation, the heat elements **606** may be a plurality of tungsten-halogen lamps for providing a tailored infrared heating means to the substrate **201**. The radiation source **646** is capable of rapidly heating the substrate **201** for thermal processing, for example at a rate of from about 50° C./s to about 280° C./s. Temperature tuning may be performed to change the temperature of the substrate **201** at certain locations while not affecting the rest of the substrate temperature. In another implementation, the radiation source **646** may be located within the chamber **636**.

[0071] The first heat unit **608** may be coupled to a first conduit **612**. The first conduit **612** may be coupled to a first gas source **628** and provide a connection between the first gas source **628** and the first gas inlet **616**. Thus, the first heat unit **608** may be operably coupled to the processing unit **624**. The first heat unit **608** may heat a first gas to a first temperature before entering the process zone **602** in the chamber **636**. The gas sources may provide process gases into the process zone **602**. In cases where a reaction using H.sub.2O, the second process gas may be hydrogen. In cases where a reaction involving N.sub.2O, the second process gas may be nitrogen. The first conduit **612** may be insulated by insulator **634** in the portion **614** that extends between the first heat unit **608** and the first gas inlet **616**. Insulating the first conduit **612** advantageously decreases heat loss as the first gas flows from the first heat unit **608** to the process zone **602**. Heating the first gas prior to entering the process zone **602** advantageously improves uniformity by decreasing the temperature gradient across the surface of the substrate **201**. Additionally, because the second gas is added to the first gas after the first gas has been heated, the two gases may react near the process zone **602**. In one implementation, the first gas is the gas that has a lower thermal conductivity and thus controls the combustion reaction. In cases where a reaction using H.sub.2O, the first gas may be oxygen. In cases where a reaction involving N.sub.2O, the first gas may be oxygen.

[0072] A coupling unit **648** may couple the portion **614** of the first conduit **612** with the chamber **636**. In one implementation, the coupling unit **648** may be silica. While the temperature of the substrate **201** may reach about 1000° C., the walls of the chamber **636** are maintained close to about 30° C. to maintain the integrity of the seals of the chamber **636**. As such, the coupling unit **648** advantageously maintains the integrity of the chamber **636** during processing of the substrate **201**.

[0073] FIG. 7 is a schematic top view of a processing system **700** that can be used to complete the flow chart **100** illustrated in FIG. 1 according to implementations described herein. One example of the processing system **700** is the CENTURA® system, available from Applied Materials, Inc., of Santa Clara, California. A transfer robot **704** of any convenient type is disposed in a transfer chamber **702** of the processing system **700**. A load-lock **706**, with two load-lock chambers **706A**, **706B** is coupled to the transfer chamber **702**. A plurality of processing chambers **708**, **710**, **712**, **714**, and **716** are also coupled to the transfer chamber **702**. The plurality of processing chamber **708**, **710**, **712**, **714**, and **716** may include at least one of the chambers described above with respect to FIGS. 2 to 6, such as a cleaning chamber, an etching chamber, an epitaxial chamber, or an oxidization chamber, etc.

[0074] Processing chamber **708** may be a cleaning chamber configured to clean a substrate prior to deposition. For example, the processing chamber **708** may be a capacitively coupled processing

chamber similar to the processing chamber **200** depicted in FIG. 2. In one implementation, the processing chamber **708** is a SICONI™ Preclean chamber, available from Applied Materials, Inc. of Santa Clara, California. The processing chamber **708** may be used to perform the cleaning process as discussed above in block **102**.

[0075] Processing chamber **710** may also be a cleaning chamber configured to clean a substrate prior to deposition. For example, the processing chamber **710** may be a pre-clean chamber using remote plasma source similar to the plasma-cleaning chamber **300** depicted in FIG. 3. In one implementation, the processing chamber **710** is an AKTIV® Pre-Clean chamber, available from Applied Materials, Inc. of Santa Clara, California. The processing chamber **710** uses electrically neutral radicals (e.g., hydrogen radicals) to react with and clean oxides and/or contaminants on a substrate as discussed above in block **102** and/or block **108**.

[0076] Processing chamber **712** may be a thermal processing chamber configured to deposit material on a substrate. For example, the processing chamber **712** may be a material deposition chamber such as an epitaxy chamber similar to the processing chamber **400** depicted in FIG. 4. In one implementation, the processing chamber **712** is a Centura® RP EPI chamber available from Applied Materials, Inc. of Santa Clara, California. The processing chamber **712** may be used to perform an epitaxial growth process as discussed above in block **104** and a purge process as discussed above in block **106**.

[0077] Processing chamber **714** may be an etching chamber configured to etch material from a substrate. For example, the processing chamber **714** may be a plasma chamber such as an ICP plasma chamber similar to the plasma chamber **500** depicted in FIG. 5. In one implementation, the processing chamber **714** is a Centura® Advantedge™ Mesa™ etch chamber, available from Applied Materials, Inc. of Santa Clara, California. The processing chamber **714** may be used to perform etch-related process as discussed above in block **108**.

[0078] Processing chamber **716** may be a thermal process chamber configured to provide a controlled thermal cycle that heats a substrate. For example, the processing chamber **716** may be a thermal process chamber similar to the processing system **600** depicted in FIG. 6. In one implementation, the processing chamber **716** is a VANTAGE® RADOX™ RTP chamber, available from Applied Materials, Inc., Santa Clara, CA. The processing chamber **716** may be used to perform downstream processing after deposition, such as thermal annealing, thermal cleaning, thermal chemical vapor deposition, thermal oxidation or thermal nitridation as discussed above in block **110**. In one example, the thermal process chamber **716** contains a radiation source having a plurality of heat elements.

[0079] During processing, a substrate that is to be processed may arrive to the processing system **700** in a pod (not shown). The substrate is transferred from the pod to the vacuum compatible load-lock **706A**, **706B** by the factory interface robot (not shown). The substrate is then handled by the transfer robot **704** in the transfer chamber **702**, which is generally kept in a vacuum state. The transfer robot **704** then loads the substrate into either processing chamber **708** or processing chamber **710** for cleaning of the substrate, as described in block **102**. Upon completion of the cleaning, the transfer robot **704** then picks up the substrate from the processing chamber **708** or **710** and loads the substrate into the processing chamber **712** for epitaxial growth of material on the substrate and chamber purging, as described in blocks **104** and **106**. The transfer robot **704** then picks up the substrate from the processing chamber **712** and loads the substrate into the processing chamber **714** for etching materials from the substrate, as described in block **108**. This sequence is repeated until a predetermined thickness of the epitaxial film is reached. Thereafter, the transfer robot **704** picks up the substrate from the processing chamber **714** and load it into the processing chamber **716** for any downstream processing, such as thermal annealing, thermal cleaning, thermal chemical vapor deposition, thermal oxidation or thermal nitridation, as discussed above in block **110**. Because all operations (blocks **102**, **104**, **106**, **108**, and **110**) are performed within the same processing system, the substrate is not exposed to atmosphere (i.e., vacuum is not broken) as the

substrate is transferred to various processing chambers, which decreases the chance of contamination and improves the quality of the deposited epitaxial film.

[0080] The transfer chamber **702** may remain under vacuum and/or at a pressure below atmosphere during the process. The vacuum level of the transfer chamber **702** may be adjusted to match the vacuum level of corresponding processing chambers. For example, when transferring a substrate from a transfer chamber **702** into a processing chamber (or vice versa), the transfer chamber **702** and the processing chamber may be maintained at the same vacuum level. Then, when transferring a substrate from the transfer chamber to the load lock chamber or batch load lock chamber (or vice versa), the transfer chamber vacuum level may match the vacuum level of the load-lock chamber **706A**, **706B** even through the vacuum level of the load-lock chamber and the processing chamber may be different.

[0081] In summary, benefits of the present disclosure provide an integrated system and method for pre-cleaning a silicon-containing substrate prior to epitaxial deposition and a cyclic deposition-etch process including an epitaxial deposition step using disilane or tetrasilane (or higher order silanes) and an etch-back step using GeH₄ and HCl, which results in an improved device quality and etch selectivity (at least 50:1) of an epitaxy process. The etch-back step using GeH₄ and HCl allows for effective removal of possible silicon nuclei from dielectric surfaces and formation of a silicon epitaxial film with much lower loss of active dopant at reduced etch temperatures (below 500° C.). With the inventive deposition-etch process, a phosphorous-containing silicon layer having a phosphorus concentration of 5.77×10^{20} atoms per cubic centimeter or greater, for example 9.49×10^{20} atoms per cubic centimeter, can be achieved without sacrificing the throughput. The high phosphorus concentration induces stress within the deposited epitaxial film, thereby increasing tensile strain, leading to increased carrier mobility and improved device performance. In addition, clustering process chambers through vacuum transfer reduces exposure to atmosphere and correspondingly reduces exposure to oxygen contaminants. Clustering the native oxide removal chambers along with the etching of silicon and epitaxial deposition also leads to a reduction in oxygen contaminants. Thus, the integrated system advantageously provides for an improved semiconductor device.

[0082] While the foregoing is directed to implementations of the present disclosure, other and further implementations of the disclosure may be devised without departing from the basic scope thereof.

Claims

1. A method of forming an epitaxial layer, comprising: flowing a processing reagent comprising a silicon source into the processing system and exposing a surface of a substrate to the processing reagent during an epitaxy process; stopping the flow of the processing reagent into the processing system; then flowing a purging gas into the processing system and pumping residues from the processing system; flowing an etching gas into the processing system and exposing the substrate to the etching gas, wherein the etching gas comprises hydrogen chloride and at least one compound selected from a germanium-containing compound, a chlorine-containing compound, or a mixture thereof; stopping the flow of the at least one compound while continuing the flow of the hydrogen chloride and exposing the substrate to the hydrogen chloride; and stopping the flow of the hydrogen chloride.

2. The method of claim 1, wherein the silicon source comprises disilane, trisilane, tetrasilane, pentasilane, or hexasilane.

3. The method of claim 1, wherein prior to the epitaxy process, further comprising exposing the surface of the substrate to a cleaning process.

4. The method of claim 3, wherein the cleaning process comprises a sputter etch process, a plasma-based oxide etch process, a wet etch process, a bake process, or combinations thereof.

5. The method of claim 3, wherein the cleaning process comprises the plasma-based oxide etch processes, which further comprises simultaneously exposing the substrate to NF.sub.3 and NH.sub.3 plasma by-products formed by a inductively coupled plasma process, a capacitively coupled plasma process, or a remote plasma assisted dry etch process.
6. The method of claim 3, wherein the cleaning process comprises heating the substrate in the presence of hydrogen gas.
7. The method of claim 3, wherein the cleaning process further comprises forming silicon-hydrogen bonds on the surface of the substrate subsequent to the removing the oxides.
8. The method of claim 3, wherein the cleaning process is performed in a pre-clean chamber comprising a capacitively coupled plasma source and a substrate support coupling to a bias RF power supply, and wherein the capacitively coupled plasma source is coupled to sources of He and NF.sub.3.
9. The method of claim 3, wherein the cleaning process comprises exposing the oxides on the surface of the substrate to an HF clean to produce —H terminations on monocrystalline silicon surfaces and —OH terminations on dielectric oxide surfaces.
10. The method of claim 1, wherein the etching gas comprises the germanium-containing compound, and wherein the germanium-containing compound comprises germanium hydride, digermane, trigermane, germanium tetrachloride, dichlorogermane, trichlorogermane, hexachlorodigermane, or any combination thereof.
11. The method of claim 1, wherein the etching gas comprises the chlorine-containing compound, and wherein the chlorine-containing compound comprises chlorine, boron trichloride, phosphorus trichloride, or any combinations thereof.
12. The method of claim 1, wherein the etching gas comprises hydrogen chloride, germanium hydride, and phosphorus trichloride.
13. The method of claim 1, wherein the etching gas further comprises a carrier gas comprising hydrogen, nitrogen, argon, helium, and any combinations thereof.
14. The method of claim 1, wherein the etching gas selectively removes an amorphous silicon from dielectric surfaces on the substrate.
15. The method of claim 1, wherein the surface of the substrate comprises contact trenches having an aspect ratio of 10:1 or greater.
16. The method of claim 1, wherein the processing system comprises an epitaxy chamber, and the epitaxy chamber comprises a liquid precursor vaporizer in fluid communication with a liquid precursor source.
17. A cluster tool for forming the epitaxial layer by the method of claim 1.
18. A method of forming an epitaxial layer, comprising: performing a process cycle which comprises: flowing a processing reagent comprising a silicon source into the processing system and exposing a surface of a substrate to the processing reagent during an epitaxy process; stopping the flow of the processing reagent into the processing system; then flowing a purging gas into the processing system and pumping residues from the processing system; flowing an etching gas into the processing system and exposing the substrate to the etching gas, wherein the etching gas comprises hydrogen chloride and at least one compound selected from a germanium-containing compound, a chlorine-containing compound, or a mixture thereof; stopping the flow of the at least one compound while continuing the flow of the hydrogen chloride and exposing the substrate to the hydrogen chloride; and stopping the flow of the hydrogen chloride; and repeating the process cycle.
19. The method of claim 18, wherein the silicon source comprises disilane, trisilane, tetrasilane, pentasilane, or hexasilane.
20. The method of claim 18, wherein the process cycle is repeated for 2 cycles to 5 cycles.
21. The method of claim 20, wherein the surface of the substrate comprises contact trenches having an aspect ratio of 10:1 or greater.
22. The method of claim 18, wherein prior to performing the process cycle, further comprising

removing oxides from the surface of the substrate within the processing system during a cleaning process.

23. The method of claim 22, wherein the cleaning process comprises the plasma-based oxide etch processes, which further comprises simultaneously exposing the substrate to NF.sub.3 and NH.sub.3 plasma by-products formed by a inductively coupled plasma process, a capacitively coupled plasma process, or a remote plasma assisted dry etch process.

24. A method of forming an epitaxial layer, comprising: removing oxides from a surface of a substrate within a processing system during a cleaning process; then flowing a processing reagent comprising disilane or tetrasilane into the processing system and exposing the substrate to the processing reagent during an epitaxy process; stopping the flow of the processing reagent into the processing system; then flowing a purging gas into the processing system and pumping residues from the processing system; flowing an etching gas into the processing system and exposing the substrate to the etching gas, wherein the etching gas comprises hydrogen chloride and at least one compound selected from a germanium-containing compound, a chlorine-containing compound, or a mixture thereof; stopping the flow of the at least one compound while continuing the flow of the hydrogen chloride and exposing the substrate to the hydrogen chloride; stopping the flow of the hydrogen chloride; and then exposing the substrate to a thermal annealing process within the processing system.
